

The latest generation of Xe plasma FIB-SEM platform enables large-volume and Ga-free sample preparation, modification and characterization. The combination of field-free UHR enabled by the BrightBeam™ SEM column and the powerful yet precise milling capabilities delivered by the new iFIB+™ Xe plasma FIB column, dramatically shortens the time needed for large-volume sample FIB-processing tasks, such as large-area cross-sectioning in packaging, MEMS and material science and enables large-scale 3D micro-characterization of any material or target applications by EDX and EBSD analysis.